

Title (en)

REDUCED RESIDUAL FORMATION IN ETCHED MULTI-LAYER STACKS

Title (de)

REDUZIERTE RESTBILDUNG IN GEÄTZTEN MEHRSCHICHTSTAPELN

Title (fr)

FORMATION RÉSIDUELLE RÉDUITE DANS DES EMPILEMENTS MULTICOUCHES GRAVÉS

Publication

**EP 2188831 B1 20151202 (EN)**

Application

**EP 08795566 A 20080825**

Priority

- US 2008010063 W 20080825
- US 95789107 P 20070824
- US 19695908 A 20080822

Abstract (en)

[origin: US2009053535A1] A multi-layer stack for imprint lithography is formed by applying a first polymerizable composition to a substrate, polymerizing the first polymerizable composition to form a first polymerized layer, applying a second polymerizable composition to the first polymerized layer, and polymerizing the second polymerizable composition to form a second polymerized layer on the first polymerized layer. The first polymerizable composition includes a polymerizable component with a glass transition temperature less than about 25° C., and the first polymerized layer is substantially impermeable to the second polymerizable composition.

IPC 8 full level

**H01L 21/302** (2006.01); **B82Y 10/00** (2011.01); **B82Y 40/00** (2011.01); **G03F 7/00** (2006.01); **G03F 7/027** (2006.01); **H01L 21/461** (2006.01)

CPC (source: EP US)

**B82Y 10/00** (2013.01 - EP US); **B82Y 40/00** (2013.01 - EP US); **G03F 7/0002** (2013.01 - EP US); **G03F 7/027** (2013.01 - EP US);  
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